

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

- 5 Claim 1 (currently amended): A cleaning ~~system, mechanism for an image~~
~~sensor package, the cleaning mechanism being cleaning the substrate and the~~
~~frame layer arranged on the substrate of the image sensor to form a chamber~~
~~between the frame layer and the substrate, the mechanism comprising:~~
 a combination of a substrate and a frame layer arranged on the substrate to
10 form a chamber together with the substrate;
 a sealed up body being formed with a cleaning room, wherein the substrate is
disposed in the cleaning room and fixed to an upper portion of the sealed up body
with the chamber facing downwards; and formed with frame layer being fixed on
the top end of the cleaning room, then, the chamber of the substrate being faced
15 down direction from the cleaning room;
 a first cleaning device being mechanism, which is disposed in the cleaning
room mounted on the bottom end of the cleaning room of the sealed up body, for
ejecting a cleaner slantingly upwards to clean cleaning the chamber of the
combination of the substrate and the frame layer. by cleaner.
- 20 Claim 2 (currently amended): The cleaning ~~mechanism-system~~ according to
claim 1, wherein the sealed up body includes a lower element, a periphery wall
connected to the lower element, and an upper cover connected to the periphery
wall, and the substrate is fixed to the upper cover.
- Claim 3 (currently amended): The cleaning ~~mechanism-system~~ according to
25 ~~claim 1, wherein further includes further comprising a vacuuming pump is~~
~~arranged within~~disposed in the cleaning room and under the chamber of the
combination of the substrate and the frame layer.
- Claim 4 (currently amended): The cleaning ~~mechanism-system~~ according to
claim 1, wherein the cleaner is nitrogen or carbon dioxide. ~~of the cleaning device~~

~~is N₂ or CO₂.~~

Claim 5 (currently amended): The cleaning ~~mechanism~~system according to claim 1, wherein the cleaner ~~of the cleaning device~~ is water.

5 Claim 6 (new): The cleaning system according to claim 1, further comprising a second cleaning mechanism disposed in the cleaning room and opposite to the first cleaning mechanism.

10 Claim 7 (new): The cleaning system according to claim 6, further comprising a vacuuming pump, which is disposed in the cleaning room and under the chamber of the combination of the substrate and the frame layer, wherein the vacuuming pump has a sucking port for sucking the cleaner, and the sucking port is disposed between the first cleaning mechanism and the second cleaning mechanism.